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(54) Title: PUSH-PULL POWER SUPPLY FOR MULTI-MESH PROCESSING CHAMBERS

(57) Abstract: A radio-frequency (RF) power circuit for a multi-electrode cathode in a processing chamber may include an RF source and inductive element(s) that are conductively coupled to the RF source. A first inductive element may be inductively coupled to the inductive element(s), and the first inductive element may be configured to receive a first portion of RF power originating from the RF source and provide the first portion of the RF power for a first pedestal electrode. A second inductive element may also be inductively coupled to the inductive element(s), and the second inductive element may be configured to receive a second portion of RF power originating from the RF source through the inductive element(s) and provide the second portion of the RF power for a second pedestal electrode.

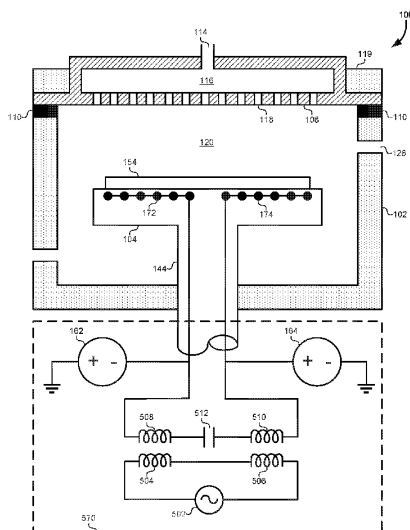


FIG. 5

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